

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Steve Biellak, et al.  
Title: System and Methods for a Wafer Inspection System Using Multiple Angles and Multiple Wavelength Illumination  
Application No.: 09/891,693 Filing Date: June 26, 2001  
Examiner: Hoa Q. Pham Group Art Unit: 2877  
Docket No.: TNCR.179US0 (M-10693 US) Conf. No.: 1752

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Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

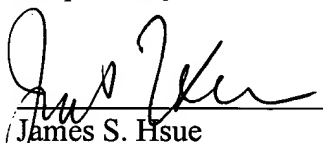
**PETITION FOR EXTENSION OF TIME**

Dear Sir:

Applicants respectfully petition for a one month extension of time within which to respond to the outstanding Office Action mailed October 19, 2004, such extension allowing the undersigned until February 22, 2005, to respond, February 19, 2005, being a Saturday, and February 21, 2005, being a holiday.

A check is enclosed that includes the amount of \$120.00 , as set forth in the enclosed transmittal letter.

Respectfully submitted,

  
James S. Hsue  
Attorney for Applicants  
Reg. No. 29,545

2/22/05  
Date

PARSONS HSUE & DE RUNTZ LLP  
655 Montgomery Street, Suite 1800  
San Francisco, CA 94111  
(415) 318-1160 (main)  
(415) 318-1163 (direct)  
(415) 693-0194 (fax)

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